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Attorney's Docket No.: 008209/USA/FEP/GCM/RKK

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Patent Application of:

Pravin K. Narwankar

Application No: 10/772,893

Filing Date: February 4, 2004

For: TAILORING NITROGEN
PROFILE IN SILICON OXYNITRIDE
USING RAPID THERMAL
ANNEALING WITH AMMONIA
UNDER ULTRA-LOW PRESSURE

Examiner:

Art Unit: 2812

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

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Please note that the following has been previously cited in and Information Disclosure Statement filed on October 19, 2004, and are not enclosed: U.S. Application Patent Publication 2002/0197884 A1 by Hiroake Niimi, et al., US Patent No.: 6,323,143 B1 by Mo-Chin Yu, US Patent No.: 6,372,578 B1 by Satoru Muramatsu, US Patent No.: 6,372,581 B1 by Daniel Bensahel, et al, and European Patent No.; DE 43 33 160 A1, "High Performance Nitrided Oxided Fabricated by Very -Low-Pressure Nitridation Technique" by Su. H.P, et al. and "Controlled Thin Oxidation and Nitridation in a Single Wafer Cluster Tool" by Sagnes I, et al.

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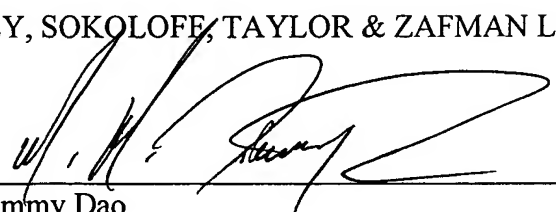
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Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

Dated: June 28, 2005



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|---|-----------------------|--|-----------------------------|---|---|
| | | | | Application Number | 10/772,893 |
| | | | | Filing Date | 02/04/2004 |
| | | | | First Named Inventor: | Pravin K. Narwankar |
| | | | | Art Unit | 2812 |
| | | | | Examiner Name | Not yet assigned |
| | | | | Attorney Docket Number | 008209/USA/FEP/GCM/RKK |
| Sheet 1 of 1 | | | | | |
| U.S. PATENT DOCUMENTS | | | | | |
| Examiner Initials* | Cite No. ¹ | Document Number | Publication Date MM-DD-YYYY | Name of Patentee or Applicant of Cited Document | Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear |
| | | Number-Kind Code ² (if known) | | | |
| | | US- 2002/0073925 A1 | 06-20-2002 | David Noble, et al. | |
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| NON PATENT LITERATURE DOCUMENTS | | | |
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| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published | T ² |
| | | Bensahel, D, et al. " Front-end, single wafer diffusion processing for advanced 300-mm fabrication lines." Microelectronics Engineering, Elsevier Publishers BV., Amsterdam, NL, vol. 56, no. 1-2, May 2001, Pages 4-59. | |
| | | Lo, G, Q, et al. "Effects of post-nitridation anneals on radiation hardness in rapid thermal nitrided gate oxides." | |
| | | PCT Search Report for PCT Application No. PC/US2004/003442. Mailed on April 7, 2005., (9 pages). | |

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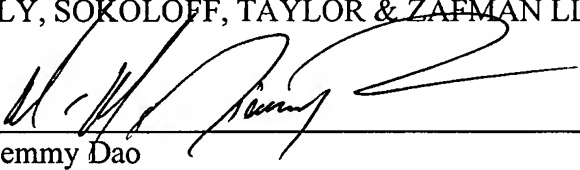
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Respectfully submitted,

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